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(12) **United States Design Patent**
Lim et al.

(10) **Patent No.:** **US D645,768 S**

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(54) **JUNCTION PHOTOVOLTAGE PROBE FACE**

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(57) **CLAIM**

The ornamental design for a junction photovoltage probe face, as shown and described.

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(**) Term: **14 Years**

DESCRIPTION

(21) Appl. No.: **29/349,483**

FIG. 1 is a perspective view of the probe showing our design; FIG. 2 is a rear side view of thereof; FIG. 3 is a top plan view thereof; FIG. 4 is a left side view thereof; FIG. 5 is a front side view thereof; FIG. 6 is right side view thereof; and, FIG. 7 is a bottom plan view thereof.

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(51) **LOC (9) Cl.** **10-04**

(52) **U.S. Cl.** **D10/78**

(58) **Field of Classification Search** D10/78,
D10/46, 75; 324/754.09, 762.01, 754.23,
324/762.05, 71.5; 356/237.2, 237.6, 432,
356/445, 418, 237.1; 257/E21.53

See application file for complete search history.

The broken lines shown of the junction photovoltage probe face in the above FIGS. 1-7 are included for the purpose of illustrating environmental structure and form no part of the claimed design.

(56) **References Cited**

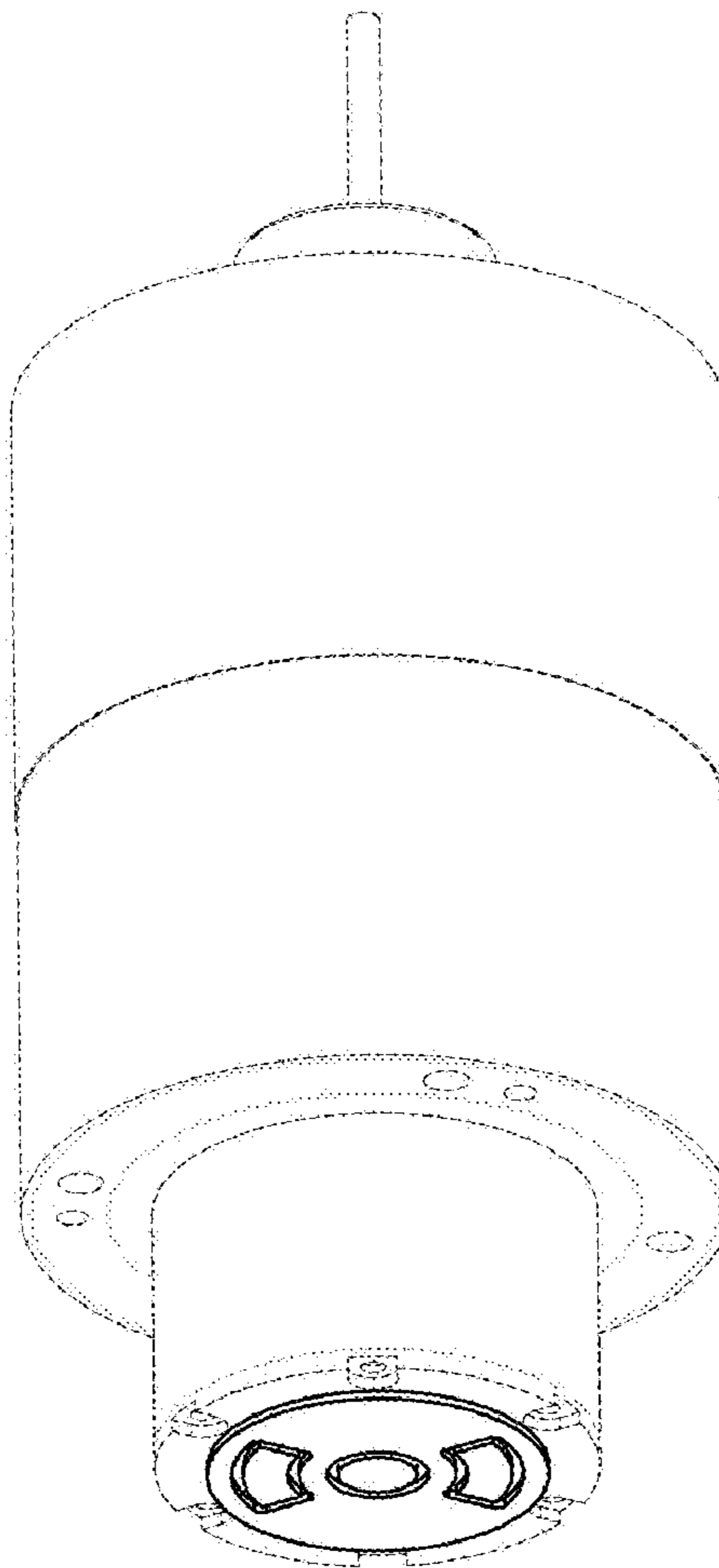
U.S. PATENT DOCUMENTS

D362,197 S * 9/1995 Fujino D10/75
D600,577 S * 9/2009 Lloyd et al. D10/75

The present design relates to an ornamental object that can be used as an input device for obtaining accurate junction photovoltage measurements of semiconductor wafers for semiconductor wafer testing equipment.

* cited by examiner

1 Claim, 7 Drawing Sheets



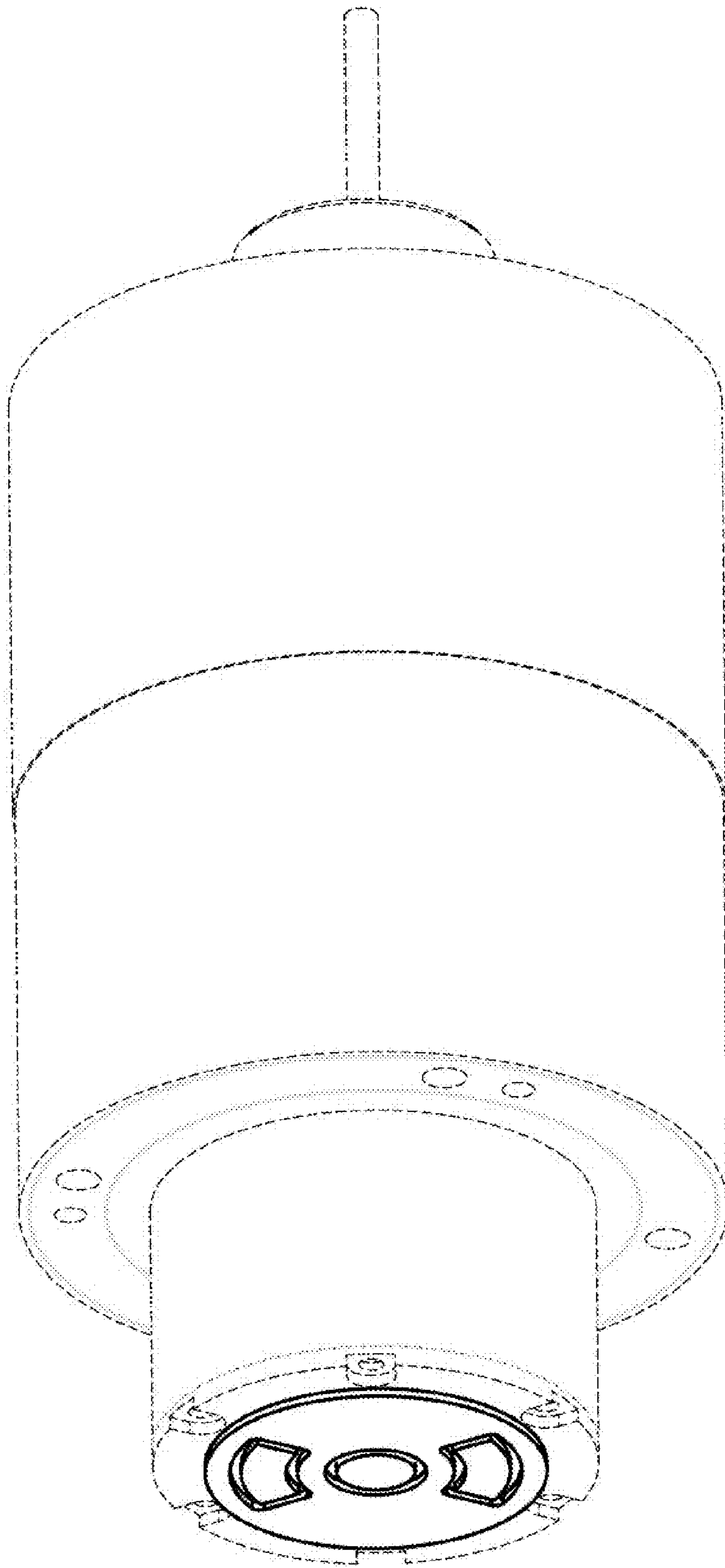


FIG. 1

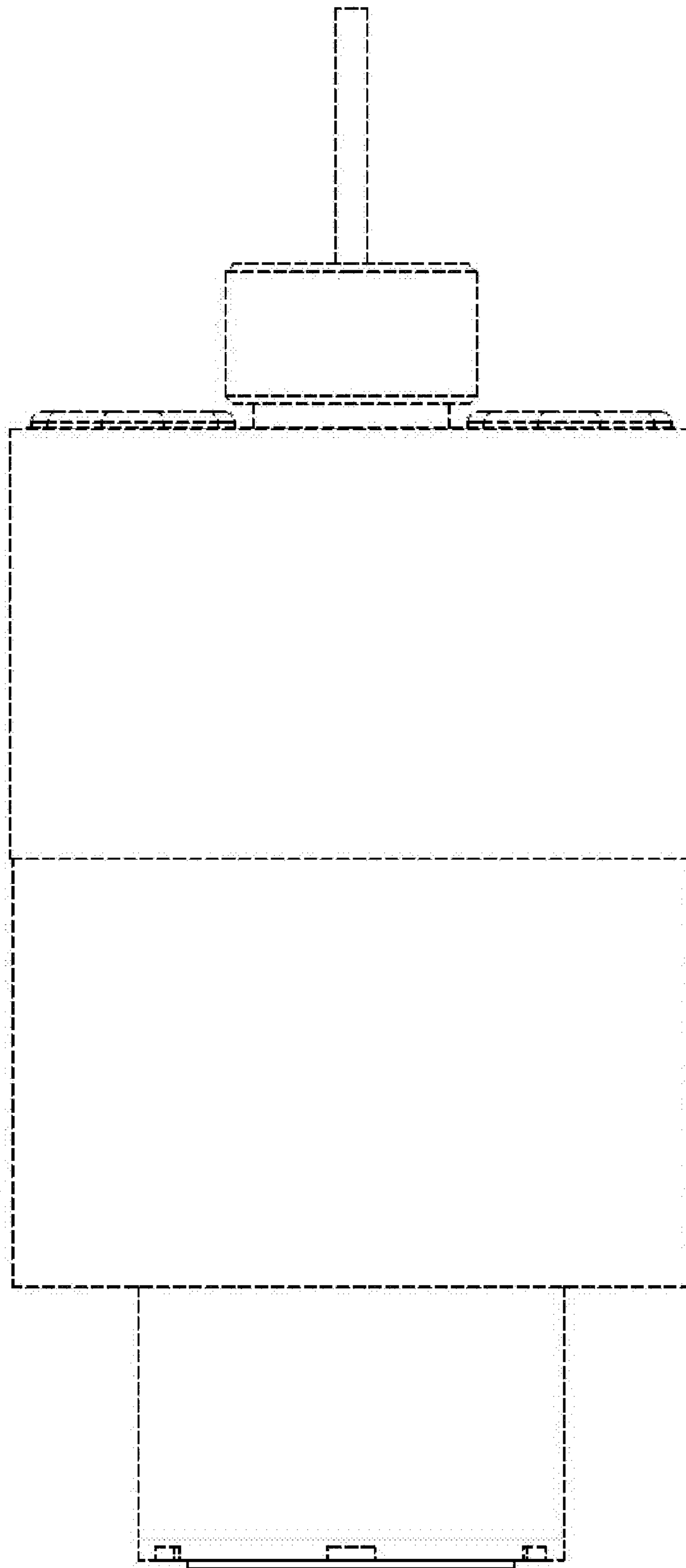


FIG. 2

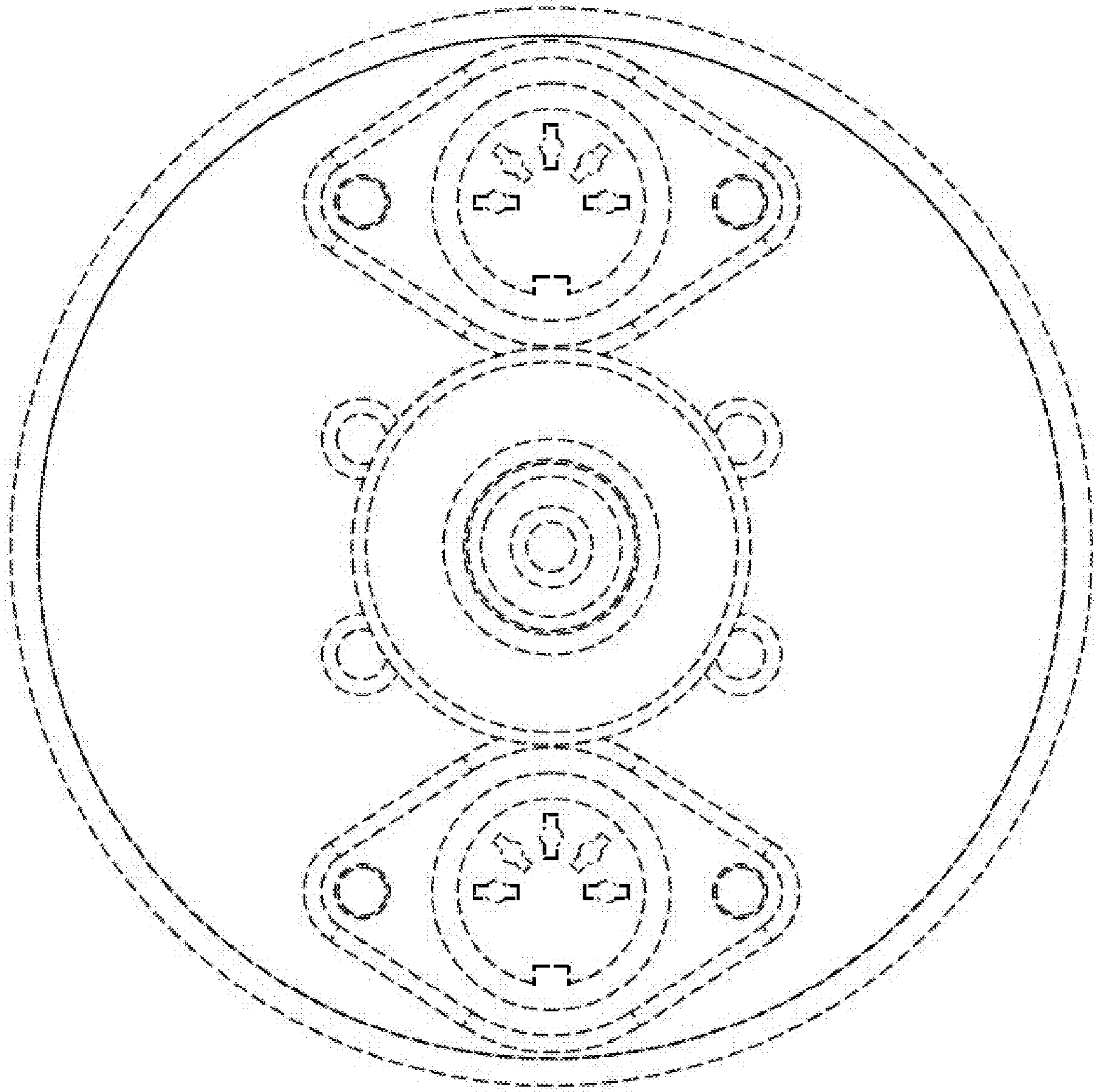


FIG. 3

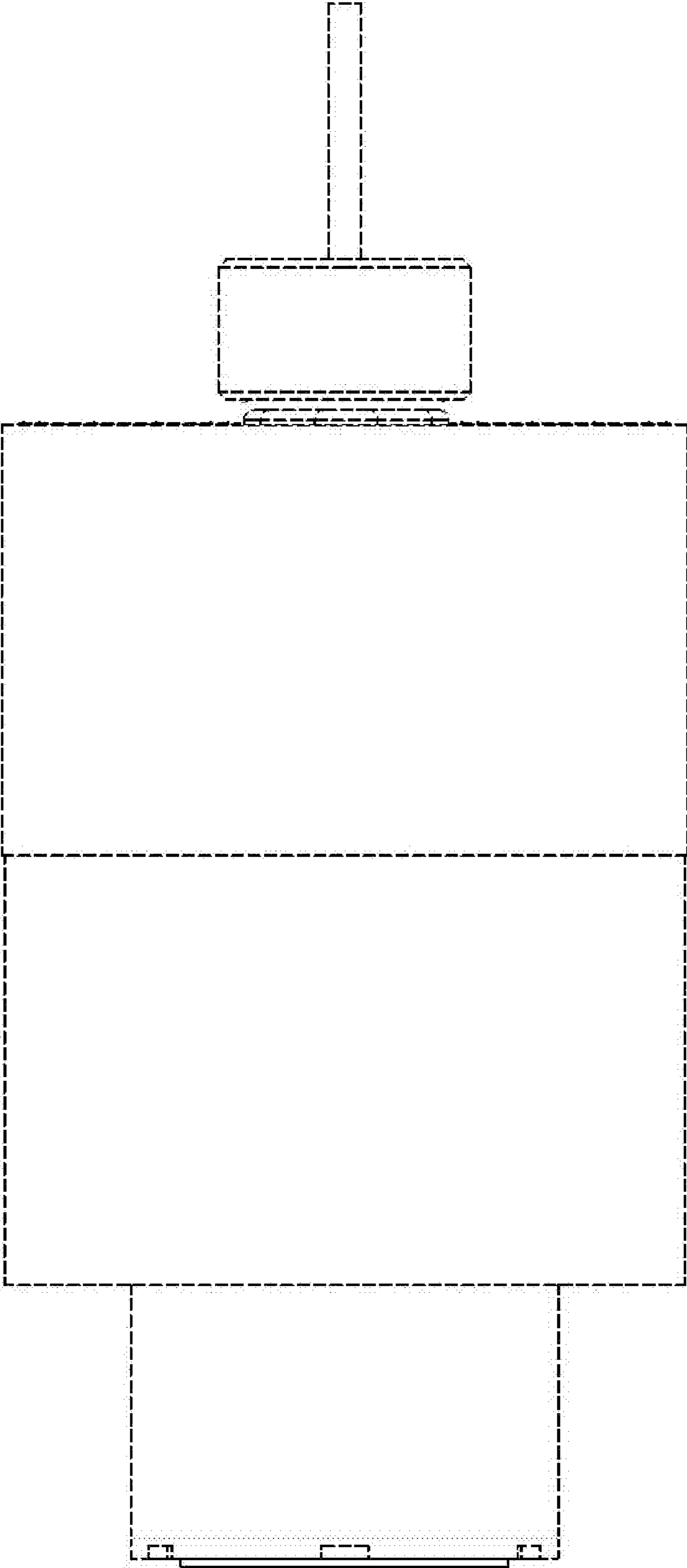


FIG. 4

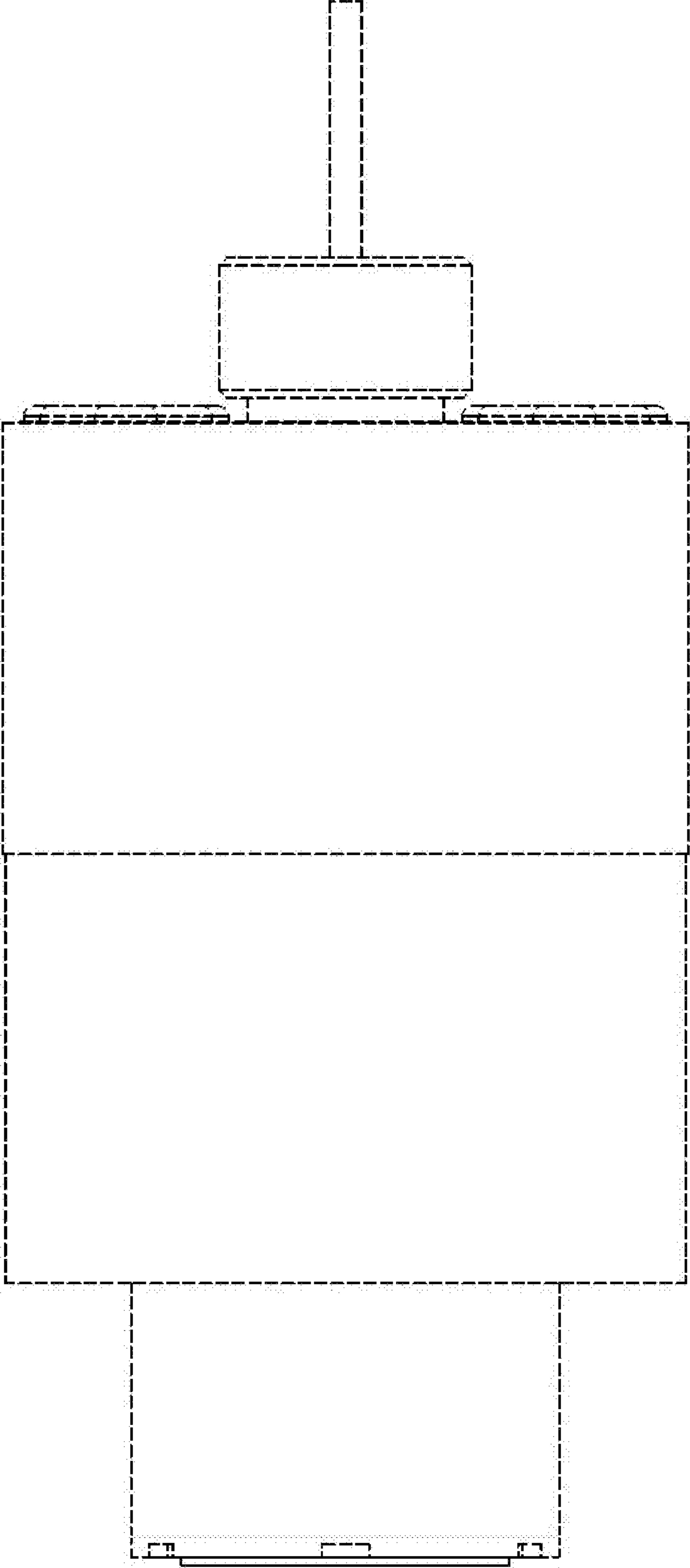


FIG. 5

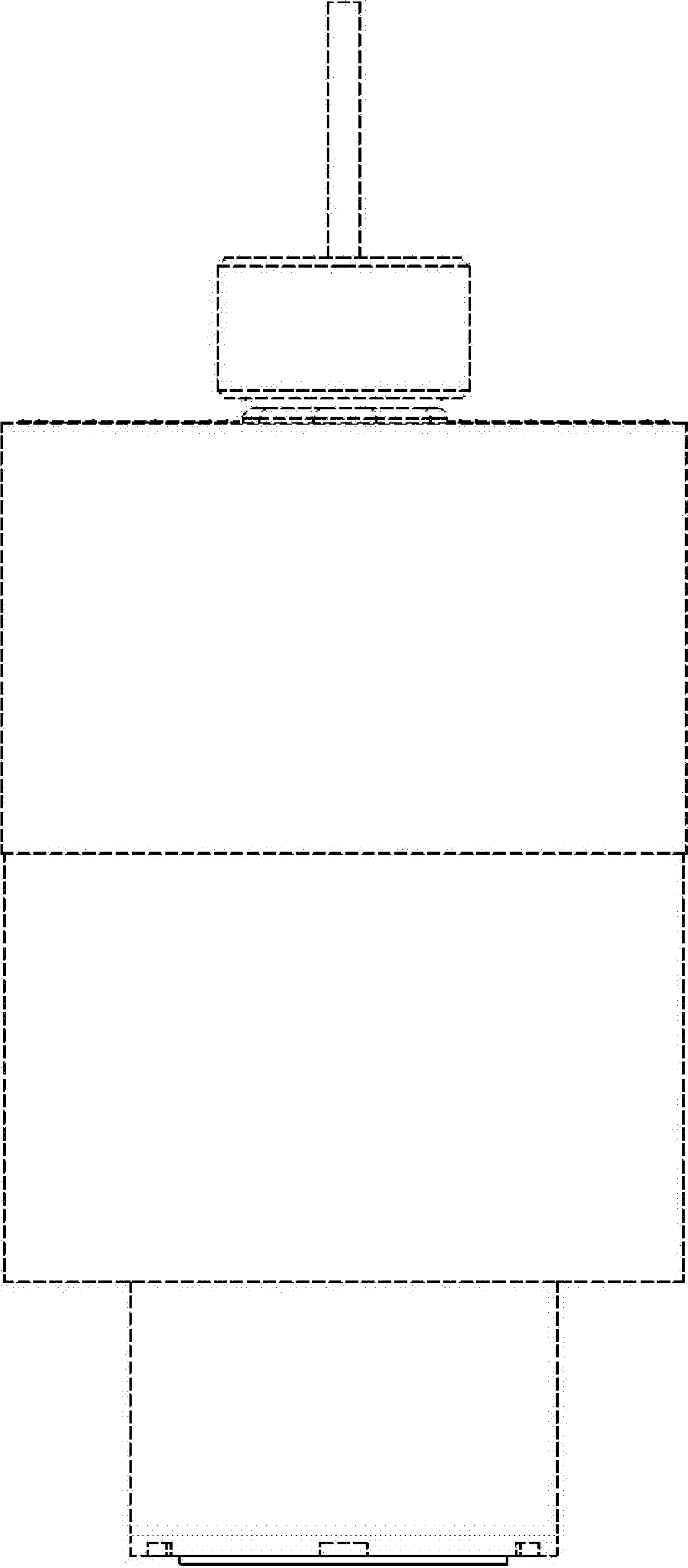


FIG. 6

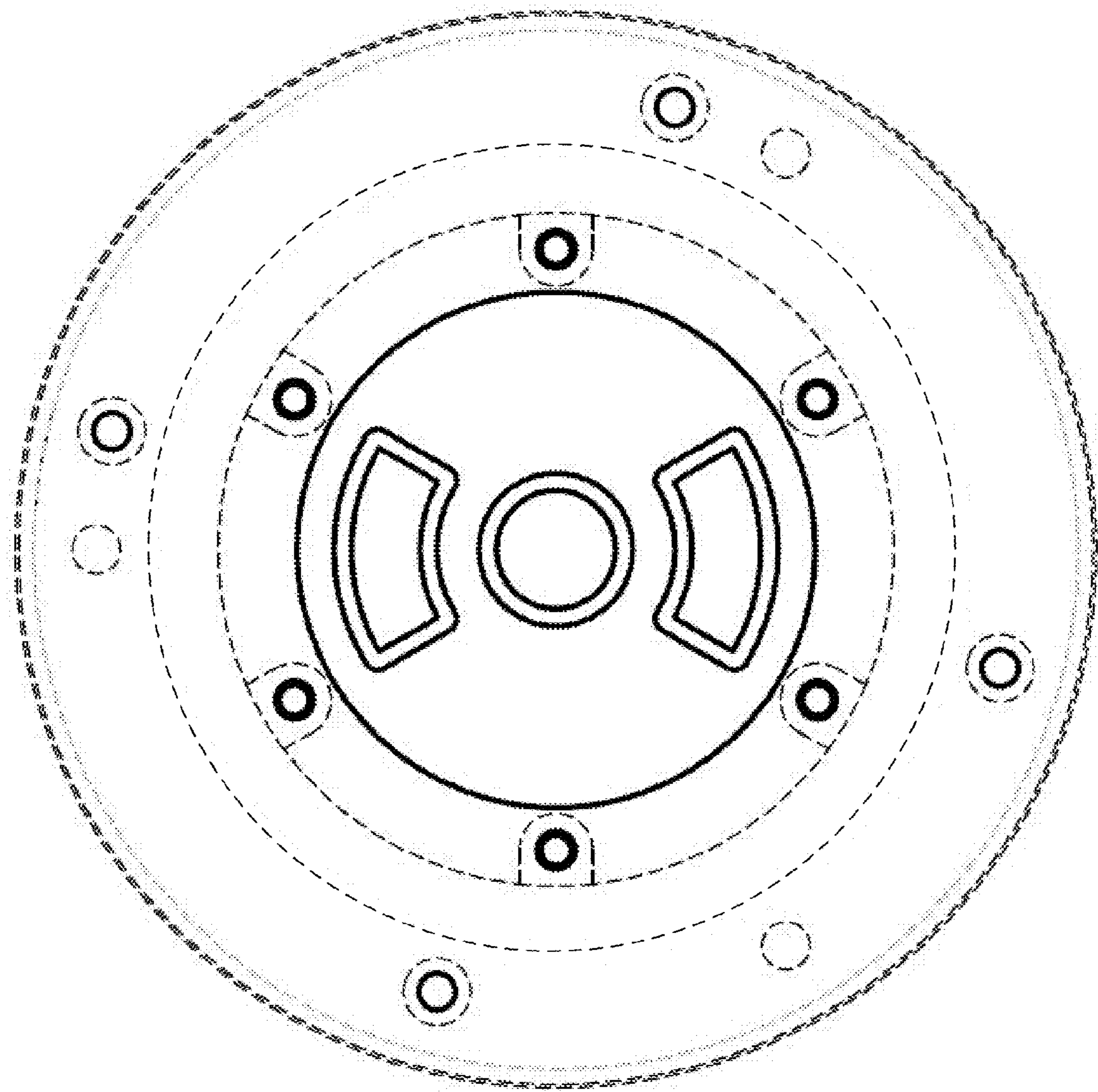


FIG. 7